

Docket No.: 061282-0048



*ZFW*  
**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of : Customer Number: 20277  
Shinya TOKUNAGA, et al. : Confirmation Number: 4744  
Application No.: 10/722,346 : Group Art Unit: 2825  
Filed: November 26, 2003 : Examiner: SIEK, VUTHE

For: MASK PATTERN INSPECTING METHOD, INSPECTION APPARATUS, INSPECTING DATA USED THEREIN AND INSPECTING DATA GENERATING METHOD

*OK to enter*

*V/S*  
*5/15/06*

**RESPONSE UNDER 37 C.F.R. § 1.111**

Mail Stop Amendment  
Honorable Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to Office Action dated February 6, 2006, having a shortened statutory period for response set to expire on Saturday, May 6, 2006, Applicants respectfully request reconsideration of the pending rejection for the following reasons.